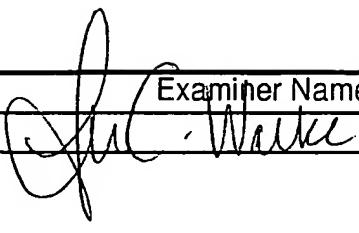


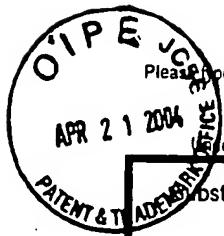
ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention	MATERIALS AND METHODS FOR IMPRINT LITHOGRAPHY																																																																																																																																																														
<p>Application Number : 10/763885 </p> <p>Confirmation Number: 6002</p> <p>First Named Applicant: Frank Xu</p> <p>Attorney Docket Number: P113-55-03</p> <p>Art Unit: 1752</p> <p>Examiner: Amanda C. Walke</p> <p>Search string: (6468642 or 5542978 or 5837314 or 6565776 or 6503914 or 6649272 or 6204343 or 4614667 or 3810874 or 6737489 or 6721529 or 6664306 or 6790905 or 6544594 or 6774183 or 6830819 or 6802870 or 5389696).pn</p>																																																																																																																																																															
<h2>US Patent Documents</h2> <p>Note: Applicant is not required to submit a paper copy of cited US Patent Documents</p> <table border="1"><thead><tr><th>init</th><th>Cite.No.</th><th>Patent No.</th><th>Date</th><th>Patentee</th><th>Kind</th><th>Class</th><th>Subclass</th></tr></thead><tbody><tr><td>XW</td><td>1</td><td>6468642</td><td>2002-10-22</td><td>Bray et al.</td><td>B1</td><td></td><td></td></tr><tr><td></td><td>2</td><td>5542978</td><td>1996-08-06</td><td>Kindt-Larsen et al.</td><td></td><td></td><td></td></tr><tr><td></td><td>3</td><td>5837314</td><td>1998-11-17</td><td>Beaton et al.</td><td></td><td></td><td></td></tr><tr><td></td><td>4</td><td>6565776</td><td>2003-05-20</td><td>Li et al.</td><td>B1</td><td></td><td></td></tr><tr><td></td><td>5</td><td>6503914</td><td>2003-01-07</td><td>Benish et al.</td><td>B1</td><td></td><td></td></tr><tr><td></td><td>6</td><td>6649272</td><td>2003-11-18</td><td>Moore et al.</td><td>B2</td><td></td><td></td></tr><tr><td></td><td>7</td><td>6204343</td><td>2001-03-20</td><td>Barucha et al.</td><td>B1</td><td></td><td></td></tr><tr><td></td><td>8</td><td>4614667</td><td>1986-09-30</td><td>Larson et al.</td><td></td><td></td><td></td></tr><tr><td></td><td>9</td><td>3810874</td><td>1974-05-14</td><td>Mitsch et al.</td><td></td><td></td><td></td></tr><tr><td></td><td>10</td><td>6737489</td><td>2004-05-18</td><td>Linert et al.</td><td>B2</td><td></td><td></td></tr><tr><td></td><td>11</td><td>6721529</td><td>2004-04-13</td><td>Chen et al.</td><td>B2</td><td></td><td></td></tr><tr><td></td><td>12</td><td>6664306</td><td>2003-12-16</td><td>Gaddam et al.</td><td>B2</td><td></td><td></td></tr><tr><td></td><td>13</td><td>6790905</td><td>2004-09-14</td><td>Fitzgerald et al.</td><td>B2</td><td></td><td></td></tr><tr><td></td><td>14</td><td>6544594</td><td>2003-04-08</td><td>Linford et al.</td><td>B2</td><td></td><td></td></tr><tr><td></td><td>15</td><td>6774183</td><td>2004-08-10</td><td>Palumbo et al.</td><td>B1</td><td></td><td></td></tr><tr><td>V</td><td>16</td><td>6830819</td><td>2004-12-14</td><td>Kaplan et al.</td><td>B2</td><td></td><td></td></tr><tr><td>V</td><td>17</td><td>6802870</td><td>2004-10-12</td><td>Chang et al.</td><td>B2</td><td></td><td></td></tr><tr><td>XW</td><td>18</td><td>5389696</td><td>1995-02-14</td><td>Dempsey et al.</td><td></td><td></td><td></td></tr></tbody></table> <p>Signature</p>								init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass	XW	1	6468642	2002-10-22	Bray et al.	B1				2	5542978	1996-08-06	Kindt-Larsen et al.					3	5837314	1998-11-17	Beaton et al.					4	6565776	2003-05-20	Li et al.	B1				5	6503914	2003-01-07	Benish et al.	B1				6	6649272	2003-11-18	Moore et al.	B2				7	6204343	2001-03-20	Barucha et al.	B1				8	4614667	1986-09-30	Larson et al.					9	3810874	1974-05-14	Mitsch et al.					10	6737489	2004-05-18	Linert et al.	B2				11	6721529	2004-04-13	Chen et al.	B2				12	6664306	2003-12-16	Gaddam et al.	B2				13	6790905	2004-09-14	Fitzgerald et al.	B2				14	6544594	2003-04-08	Linford et al.	B2				15	6774183	2004-08-10	Palumbo et al.	B1			V	16	6830819	2004-12-14	Kaplan et al.	B2			V	17	6802870	2004-10-12	Chang et al.	B2			XW	18	5389696	1995-02-14	Dempsey et al.			
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 John Wallace	June 8, 2005



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Application Number	10/763,885
Filing Date	01/23/2004
First Named Inventor	Xu et al.
Group Art Unit	Unassigned
Examiner Name	Unassigned
Attorney Docket Number	P113/MII-79-61-03

U.S. PATENT DOCUMENTS

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Filing Date	01/23/2004
First Named Inventor	Xu et al.
Group Art Unit	Unassigned
Examiner Name	Unassigned
Attorney Docket Number	P113/MII-79-61-03

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First Named Inventor	Xu et al.
Group Art Unit	Unassigned
Examiner Name	Unassigned
Attorney Docket Number	P113/MII-79-61-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

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	A18	KRUG et al., "Fine Patterning of Thin Sol-Gel Films," Journal of Non-Crystalline Solids, 1992, pp. 447-450, vol. 147 & 148.	
ACW	A19	Krauss et al., "Fabrication of Nanodevices Using Sub-25nm Imprint Lithography," Appl. Phys. Lett 67(21), 3114-3116, 1995	
	A20	CHOU et al., "Imprint of Sub-25 nm Vias and Trenches in Polymers," Applied Physics Letters, November 20, 1995, pp. 3114-3116, vol. 67(21).	
	A21	CHOU et al., "Imprint Lithography with 25-Nanometer Resolution," Science, Apr. 5, 1996, pp. 85-87, vol. 272.	
	A22	HAISMA et al., "Mold-Assisted Nanolithography: A Process for Reliable Pattern Replication," Journal of Vacuum Science and Technology, Nov/Dec 1996, pp. 4124-4128, vol. B 14(6).	
	A23	CHOU et al., "Imprint Lithography with Sub-10nm Feature Size and High Throughput," Microelectronic Engineering, 1997, pp. 237-240, vol. 35.	
	A24	FELDMAN et al., "Wafer chuck for manification correction in x-ray lithography," American Vacuum Society, 1998, pp. 3476-3479.	
	A25	SCHEER et al., "Problems of the Nanoimprinting Technique for Nanometer Scale Pattern Definition," Journal of Vacuum Science and Technology, Nov/Dec 1998, pp. 3917-3921, vol. B 16(6).	
	A26	COLBURN et al., "Step and Flash Imprint Lithography: A New Approach to High-Resolution Patterning", Proc. of SPIE, 1999, pp. 379-389, vol. 3676.	
	A27	CHOU et al., "Lithographically-Induced Self Assembly of Periodic Polymer Micropillar Arrays," Journal of Vacuum Science and Technology, Nov/Dec 1999, pp. 3197-3202, vol. B 17(6).	
ACW	A28	RUCHHOEFT et al., "Patterning Curved Surfaces: Template Generation by Ion Beam Proximity Lithography and Relief Transfer by Step and Flash Imprint Lithography," Journal of Vacuum Science and Technology, 1999, pp. 2965-2982, vol. 17.	

Examiner Signature

Julia C. Walker

Date Considered

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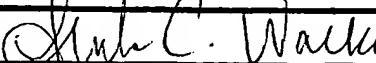
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ACW	A29	CHOI et al., "Design of Orientation Stages for Step and Flash Imprint Lithography," Precision Engineering, Journal of the International Societies for Precision Engineering and Nanotechnology, 2001, pp. 192-199, vol. 25.	
	A30	CHOI et al., "High Precision Orientation Alignment and Gap Control Stages for Imprint Lithography Processes," U.S. Patent Application 09/698,317. Filed with USPTO on October 27, 2000.	
	A31	SREENIVASAN et al., "High-Resolution Overlay Alignment Methods and Systems for Imprint Lithography," U.S. Patent Application Publication 2002/0098426. Published on July 25, 2002.	
	A32	CHOI et al., "Method and System of Automatic Fluid Dispensing for Imprint Lithography Processes," U.S. Patent Application Publication 2002/0094496. Published on July 18, 2002.	
	A33	CHOI et al., "Methods for High-Precision Gap and Orientation Sensing Between a Transparent Template and Substrate for Imprint Lithography," U.S. Patent Application Publication 2003/0093122. Published on July 18, 2002.	
	A34	VOISIN, "Methods of Manufacturing a Lithography Template," U.S. Patent Application Publication 2003/0205657. Published on November 6, 2003.	
	A35	SREENIVASAN et al., "Step and Repeat Imprint Lithography Systems," U.S. Patent Application Publication 2004/0008334. Published on January 15, 2004.	
	A36	SREENIVASAN et al., "Step and Repeat Imprint Lithography Processes," U.S. Patent Application 10/194,991. Filed with USPTO July 11, 2002.	
	A37	OTTO M. et al., "Step and Repeat UV-Nanoimprint Lithography: Material Issues," Nanoimprint and Nanoprint Technology Conference, San Francisco, December 11-13, 2002.	
	A38	JOHNSON, et al., "Advances in Step and Flash Imprint Lithography," SPIE Microlithography Conference, February 23-28, 2003.	
ACW	A39	CHOI et al., "A Chucking System and Method for Modulating Shapes of Substrates," U.S. Patent Application 10/293,224. Filed with USPTO on November 13, 2002.	

Examiner Signature		Date Considered	1/18/05
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Application Number	10/763,885
Filing Date	01/23/2004
First Named Inventor	Xu et al.
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Attorney Docket Number	P113/MII-79-61-03

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ANW	A40	VOISIN, "Methods of Inspecting A Lithography Template," U.S. Patent Application 10/293,919. Filed with USPTO on November 13, 2002	
	A41	CHOI et al., "A Method For Modulating Shapes of Substrates," U.S. Patent Application 10/316,963. Filed with USPTO on December 11, 2002.	
	A42	CHOI et al., "A Conforming Template For Patterning Liquids Disposed On Substrates," U.S. Patent Application 10/614,716. Filed with USPTO on July 7, 2003.	
	A43	NIMMAKAYALA et al., "Magnification Correction Employing Out-of-Plane Distortion of a Substrate," U.S. Patent Application 10/735,110. Filed with USPTO on December 12, 2003.	
✓	A44	SREENIVASAN et al., "Method For Concurrently Employing Differing Materials To Form A Layer On A Substrate," U.S. Patent Application 10/760,821. Filed with USPTO January 20, 2004.	
ANW	A45	SREENIVASAN, " Full-Wafer Or Large Area Imprinting With Multiple Separated Sub-Fields For High Throughput Lithography," U.S. Patent Application 10/788,700. Filed with USPTO on February 27, 2004.	

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John C. Walker

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Sheet

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Application Number	10/763,885
Filing Date	01/23/2004
First Named Inventor	Xu et al.
Group Art Unit	1752
Examiner Name	Amanda C. Walke
Attorney Docket Number	P113-55-03

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	U.S. Patent Document Number	Kind Code ² (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
ACW	B1	3,527,062		Bilinski et al.	09-08-1970	
	B2	3,783,520		King	01-08-1974	
	B3	3,807,027		Heisler	04-30-1974	
	B4	3,807,029		Troeger	04-30-1974	
	B5	3,811,665		Seelig	05-21-1974	
	B6	4,062,600		Wyse	12-13-1977	
	B7	4,070,116		Frosch et al.	01-24-1978	
	B8	4,098,001		Watson	07-04-1978	
	B9	4,119,688		Hiraoka	10-10-1978	
	B10	4,119,688		Hiraoka	10-10-1978	
	B11	4,155,169		Drake et al.	05-22-1979	
	B12	4,201,800		Alcorn et al.	05-06-1980	
	B13	4,202,107		Watson	05-13-1980	
	B14	4,267,212		Sakawaki	05-12-1981	
	B15	4,326,805		Feldman et al.	04-27-1982	
	B16	4,337,579		De Fazio	07-06-1982	
	B17	4,355,469		Nevins et al.	10-26-1982	
	B18	4,414,750		De Fazio	11-15-1983	
	B19	4,426,247		Toshiakai et al.	01-17-1984	
	B20	4,440,804		Milgram	04-03-1984	
	B21	4,451,507		Beltz et al.	05-29-1994	
	B22	4,507,331		Hiraoka	03-02-1985	
	B23	4,544,572		Sandvig et al.	10-01-1985	
	B24	4,552,832		Blume et al.	11-12-1985	
	B25	4,552,833		Ito et al.	11-12-1985	
	B26	4,600,309		Fay	07-15-1986	
	B27	4,610,442		Oku et al.	09-09-1986	
	B28	4,657,845		Frechet et al.	04-04-1987	
	B29	4,692,205		Sachdev et al.	09-08-1987	
	B30	4,694,703		Routson	09-22-1987	
	B31	4,707,218		Giammarco et al.	11-17-1987	
	B32	4,737,425		LIN et al.	04-12-1988	
	B33	4,763,886		Takei	08-16-1988	
ACW	B34	4,808,511		Holmes	02-28-1989	

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Amanda C. Walke

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

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of

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Complete if Known

Application Number	10/763,885
Filing Date	01/23/2004
First Named Inventor	Xu et al.
Group Art Unit	1752
Examiner Name	Amanda C. Walke

Attorney Docket Number

P113-55-03

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
<i>AM</i>	B35	4,826,943		Ito et al.	05-02-1989	
	B36	4,846,931		Gmitter et al.	07-11-1989	
	B37	4,848,911		Uchida et al.	07-18-1989	
	B38	4,857,477		Kanamori	08-15-1989	
	B39	4,883,561		Gmitter et al.	11-28-1989	
	B40	4,891,303		Garza et al.	01-02-1990	
	B41	4,908,298		Hefferon et al.	03-13-1990	
	B42	4,919,748		Bredbenner et al.	04-24-1990	
	B43	4,921,778		Thackeray et al.	05-01-1990	
	B44	4,929,083		Brunner	05-29-1990	
	B45	4,931,351		McColgin et al.	06-05-1990	
	B46	4,959,252		Bonnebat et al.	09-25-1990	
	B47	4,964,945		Calhoun	10-23-1990	
	B48	4,976,818		Hashimoto et al.	12-11-1990	
	B49	4,980,316		Huebner	12-25-1990	
	B50	4,999,280		Hiraoka	03-12-1990	
	B51	5,053,318		Gulla et al.	10-01-1991	
	B52	5,063,321		Carter	11-05-1991	
	B53	5,071,694		Uekita et al.	12-10-1991	
	B54	5,072,126		Progler	12-10-1991	
	B55	5,073,230		Maracas et al.	12-17-1991	
	B56	5,074,667		Miyatake	12-24-1991	
	B57	5,108,875		Thackeray et al.	04-28-1992	
	B58	5,110,514		Soane	05-05-1992	
	B59	5,126,006		Cronin et al.	06-30-1992	
	B60	5,148,036		Matsugu et al.	09-15-1992	
	B61	5,148,037		Suda et al.	09-15-1992	
	B62	5,151,754		Ishibashi et al.	09-29-1992	
	B63	5,169,494		Hashimoto et al.	12-08-1992	
	B64	5,173,393		Sezi et al.	12-22-1992	
	B65	5,179,863		Uchida et al.	01-19-1993	
	B66	5,198,326		Hashimoto et al.	03-30-1993	
	B67	5,204,739		Domenicall	04-20-1993	
<i>AM</i>	B68	5,205,983		Guckel et al.	05-04-1993	

Examiner Signature

Amanda C. Walke

Date Considered

June 8, 2005

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Sheet

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Complete if Known

Application Number	10/763,885
Filing Date	01/23/2004
First Named Inventor	Xu et al.
Group Art Unit	1752
Examiner Name	Amanda C. Walke
Attorney Docket Number	P113-55-03

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (If known)			
ACW	B69	5,212,147		Sheats	05-18-1993	
	B70	5,234,793		Sebald et al.	08-10-1993	
	B71	5,240,550		Boehnke et al.	08-31-1993	
	B72	5,240,878		Fizsimmons et al.	08-31-1993	
	B73	5,242,711		DeNatale et al.	09-07-1993	
	B74	5,244,818		Jokerst et al.	09-14-1993	
	B75	5,259,926		Kuwabara et al.	09-09-1993	
	B76	5,270,984	A	Mine	12-14-1993	
	B77	5,277,749		Griffith et al.	01-11-1994	
	B78	5,314,772		Kozicki et al.	05-24-1994	
	B79	5,318,870		Hartney	06-07-1994	
	B80	5,324,683		Fitch et al.	06-28-1994	
	B81	5,328,810		Lowrey et al.	07-12-1994	
	B82	5,330,881		Sidman et al.	07-19-1994	
	B83	5,348,616		Hartman et al.	09-20-1994	
	B84	5,362,606		Hartney et al.	11-08-1994	
	B85	5,366,851		Novembre	11-22-1994	
	B86	5,374,454		Bickford et al.	12-20-1994	
	B87	5,376,810		Hoenk et al.	12-27-1994	
	B88	5,380,474		Rye et al.	01-10-1995	
	B89	5,392,123		Marcus et al.	02-21-1995	
	B90	5,417,802		Obeng	05-23-1995	
	B91	5,421,981		Leader et al.	06-06-1995	
	B92	5,422,295		Choi et al.	06-06-1995	
	B93	5,424,549		Feldman	06-13-1995	
	B94	5,425,964		Southwell et al.	06-20-1995	
	B95	5,431,777		Austin et al.	07-11-1995	
	B96	5,439,766		Day et al.	08-08-1995	
	B97	5,452,090		Progler et al.	09-19-1995	
	B98	5,453,157		Jeng	09-26-1995	
	B99	5,458,520		DeMercurio et al.	10-17-1995	
V	B100	5,468,542		Crouch	11-21-1995	
V	B101	5,480,047		Tanigawa et al.	01-02-1996	
ACW	INTENTIONAL		BLANK			
Examiner Signature	<i>Amanda C. Walke</i>			Date Considered	<i>June 8, 2005</i>	

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Sheet

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Application Number	10/763,885
Filing Date	01/23/2004
First Named Inventor	Xu et al.
Group Art Unit	1752
Examiner Name	Amanda C. Walke

Attorney Docket Number P113-55-03

U.S. PATENT DOCUMENTS

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		Number	Kind Code ² (if known)			
	B102	5,515,167		Ledger et al.	05-07-1996	
	B103	5,523,878		Wallace et al.	06-04-1996	
	B104	5,527,662		Hashimoto et al.	06-18-1996	
	B105	5,545,367		Bae et al.	08-13-1996	
	B106	5,566,584		Briganti	10-22-1996	
	B107	5,633,505		Chung et al.	05-27-1997	
	B108	5,654,238		Cronin et al.	08-05-1997	
	B109	5,670,415		Rust	09-23-1997	
	B110	5,700,626		Lee et al.	12-23-1997	
	B111	5,723,176		Keyworth et al.	03-03-1998	
	B112	5,724,145		Kondo et al.	03-03-1998	
	B113	5,725,788		Maracas et al.	03-10-1998	
	B114	5,736,424		Prybyla et al.	04-07-1998	
	B115	5,743,998		Park	04-28-1998	
	B116	5,747,102		Smith et al.	05-05-1998	
	B117	5,753,014		Van Rijn	05-19-1998	
	B118	5,760,500		Kondo et al.	06-02-1998	
	B119	5,776,748		Singhvi et al.	07-07-1998	
	B120	5,779,799		Davis	07-14-1998	
	B121	5,802,914		Fassler et al.	09-08-1998	
	B122	5,855,686		Rust	01-05-1999	
	B123	5,877,036		Kawai	03-02-1999	
	B124	5,877,861		Ausschnitt et al.	03-02-1999	
	B125	5,888,650		Calhoun et al.	03-30-1999	
	B126	5,895,263		Carter et al.	04-20-1999	
	B127	5,907,782		Wu	05-25-1999	
	B128	5,912,049		Shirley	06-15-1999	
	B129	5,926,690		Toprac et al.	07-20-1999	
	B130	5,937,758		Maracas et al.	08-17-1999	
	B131	5,942,871		Lee	08-24-1999	
	B132	5,948,219		Rohner	09-07-1999	
	B133	5,948,470		Harrison et al.	09-07-1999	
	B134	5,952,127		Yamanaka	09-14-1999	
	B135	6,033,977		Gutsche et al.	03-07-2000	

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

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of

17

Application Number	10/763,885
Filing Date	01/23/2004
First Named Inventor	Xu et al.
Group Art Unit	1752
Examiner Name	Amanda C. Walke

Attorney Docket Number P113-55-03

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		Number	Kind Code ² (if known)			
ACW	B136	6,035,805		Rust	03-14-2000	
	B137	6,038,280		Rossiger et al.	03-14-2000	
	B138	6,046,056		Parce et al.	04-04-2000	
	B139	6,051,345		Huang	04-18-2000	
	B140	6,074,827		Nelson et al.	06-13-2000	
	B141	6,091,485		Li et al.	07-18-2000	
	B142	6,096,655		Lee et al.	08-01-2000	
	B143	6,117,708		Wensel	09-12-2000	
	B144	6,125,183		Jiawook et al.	09-26-2000	
	B145	6,128,085		Buermann et al.	10-03-2000	
	B146	6,143,412		Schueller et al.	11-07-2000	
	B147	6,150,231		Muller et al.	11-21-2000	
	B148	6,150,680		Eastman et al.	11-21-2000	
	B149	6,168,845		Fontana Jr. et al.	01-02-2001	
	B150	6,180,239	B1	Whitesides et al.	01-30-2001	
	B151	6,188,150	B1	Spence	02-13-2001	
	B152	6,204,922	B1	Chalmers	03-20-2001	
	B153	6,218,316	B1	Marsh	04-17-2001	
	B154	6,245,581	B1	Bonser et al.	06-12-2001	
	B155	6,274,294	B1	Hines	08-14-2001	
	B156	6,326,627	B1	Putvinski et al.	12-04-2001	
	B157	6,329,256	B1	Ibok	12-11-2001	
	B158	6,355,198	B1	Kim et al.	03-12-2002	
	B159	6,387,783		Furukawa et al.	05-14-2002	
	B160	6,388,253	B1	Su	05-14-2002	
	B161	6,391,798	B1	DeFelice et al.	05-21-2002	
	B162	6,411,010	B1	Suzuki et al.	06-25-2002	
	B163	6,447,919	B1	Brown et al.	09-10-2002	
	B164	6,455,411	B1	Jiang et al.	09-24-2002	
	B165	6,467,761	B1	Amatucci et al.	10-22-2002	
	B166	6,482,742	B1	Chou	11-19-2002	
ACW	B167	6,489,068	B1	Kye	12-03-2002	
	B168	6,495,624	B1	Brown, James F.	12-17-2002	
ACW	B169	6,514,672	B2	Young et al.	02-04-2003	

Examiner Signature

A.C. Walke

Date Considered

June 8, 2005

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Substitute for form 1449A/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Application Number	10/763,885
Sheet	6	of	17	Filing Date	01/23/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1752
				Examiner Name	Amanda C. Walke
				Attorney Docket Number	P113-55-03

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		Number	Kind Code ⁴ (if known)			
ACW	B170	6,534,418	B1	Plat et al.	03-18-2003	
	B171	6,541,360	B1	Plat et al.	04-01-2003	
	B172	6,561,706		Singh et al.	05-13-2003	
	B173	6,565,928	B2	Sakamoto et al.	05-20-2003	
	B174	6,632,742	B2	Yang et al.	10-14-2003	
	B175	6,635,581	B2	Wong	10-21-2003	
	B176	6,646,662	B1	Nebashi et al.	11-11-2003	
	B177	6,677,252	B2	Marsh	01-13-2004	
	B178	6,703,190	B2	Elian	03-09-2004	
	B179	6,713,238	B1	Chou et al.	03-30-2004	
	B180	6,716,767	B2	Shih et al.	04-06-2004	
	B181	6,719,915	B2	Willson et al.	04-13-2004	
	B182	6,730,256	B1	Bloomstein et al.	05-04-2004	
	B183	6,737,202	B2	Gehoski et al.	05-18-2004	
	B184	6,743,713	B2	Mukherjee-Roy et al.	06-01-2004	
	B185	6,767,983	B1	Fujiyama et al.	07-27-2004	
	B186	6,770,852	B1	Steger	08-03-2004	
	B187	6,776,094	B1	Whitesides et al.	08-17-2004	
	B188	6,777,170	B1	Bloomstein et al.	08-17-2004	
	B189	2002/0132482		Chou	09-19-2002	
	B190	2002/0150398	A1	Choi et al.	10-17-2002	
	B191	2002/0167117		Chou	11-14-2002	
	B192	2003/0080471		Chou	05-01-2003	
	B193	2003/0081193		White et al.	05-01-2003	
	B194	2003/0113638	A1	Mancini et al.	06-19-2003	
	B195	2003/0129542	A1	Shih et al.	07-10-2003	
	B196	2003/0205658	A1	Volsin	11-06-2003	
	B197	2003/0215577	A1	Willson et al.	11-20-2003	
	B198	2003/0235787	A1	Watts et al.	12-25-2003	
	B199	2004/0009673	A1	Sreenivasan et al.	01-15-2004	
ACW	B200	2004/0010341	A1	Watts et al.	01-15-2004	
	B201	2004/0029041	A1	Shih et al.	02-12-2004	
	B202	2004/0036201	A1	Chou et al.	02-26-2004	
ACW	B203	2004/0053146	A1	Sreenivasan et al.	03-18-2004	

Examiner Signature

Amanda C. Walke

Date Considered

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Substitute for form 1449A/PTO				Complete if Known	
				Application Number	10/763,885
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				First Named Inventor	Xu et al.
				Group Art Unit	1752
				Examiner Name	Amanda C. Walke
Sheet	7	of	17	Attorney Docket Number	
P113-55-03					

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Examiner Initials*	Cle No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY
		Number	Kind Code ² (if known)		
<i>AM</i>	B204	2004/0086793	A1	Sreenivasan et al.	05-06-2004
	B205	2004/0089979	A1	Rubin	05-13-2004
	B206	2004/0090611	A1	Choi et al.	05-13-2004
	B207	2004/0104641	A1	Choi et al.	06-03-2004
	B208	2004/0112861	A1	Choi et al.	06-17-2004
	B209	2004/0112862	A1	Willson et al.	06-17-2004
	B210	2004/0116548	A1	Willson et al.	06-17-2004
	B211	2004/0124566	A1	Sreenivasan et al.	07-01-2004
	B212	2004/0141163	A1	Bailey et al.	07-22-2004
	B213	2004/0141168	A1	Sreenivasan et al.	07-22-2004
	B214	2004/0149687	A1	Choi et al.	08-05-2004
	B215	2004/0163563	A1	Sreenivasan et al.	08-26-2004
	B216	2004/0168586	A1	Bailey et al.	09-02-2004
	B217	2004/0168588	A1	Choi et al.	09-02-2004
	B218	2004/0168613	A1	Nguyen	09-02-2004
	B219	2004/0169441	A1	Choi et al.	09-02-2004
	B220	2004/0170770	A1	Nguyen	09-02-2004
	B221	2004/0170771	A1	Bailey et al.	09-02-2004
	B222	2004/0188381	A1	Sreenivasan et al.	09-30-2004
	B223	2004/0189994	A1	Sreenivasan et al.	09-30-2004
	B224	2004/0189996	A1	Sreenivasan et al.	09-30-2004
	B225	2004/0200411	A1	Willson et al.	10-14-2004
<i>ACW</i>	B226	2004/0202865		Homola et al.	10-14-2004
	B227	2004/0209177	A1	Sreenivasan et al.	10-21-2004
	B228	6,383,928	B1	Eissa	05-07-2002
Examiner Signature	<i>Amanda C. Walke</i>			Date Considered	<i>July 8, 2005</i>

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Application Number	10/763,885
				Filing Date	01/23/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1752
				Examiner Name	Amanda C. Walke
Sheet	8	of	17	Attorney Docket Number	
P113-55-03					

FOREIGN PATENT DOCUMENTS

Examiner Signature	Juli C. Walko	Date Considered	June 8, 2015
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Application Number	10/763,885
Filing Date	01/23/2004
First Named Inventor	Xu et al.
Group Art Unit	1752
Examiner Name	Amanda C. Walke
Attorney Docket Number	P113-55-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
ACW	B249	Abstract of Japanese Patent 02-24848, January 26, 1990	
	B250	Abstract of Japanese Patent 02-92603, August 12, 2004	
	B251	Abstract of Japanese Patent 55-88332, April 14, 2004	
	B252	Abstract of Japanese Patent 57-7931, April 14, 2004	
	B253	Abstract of Japanese Patent 63-138730, April 14, 2004	
	B254	ANANTHASURESH et al., "Strategies for Systematic Synthesis of Compliant Mems.", DSC-Vol. 55-2, Dynamic Systems and Control: Volume 2, pp. 677 – 686, November 1, 1994.	
	B255	ARAI et al., "Calibration and Basic Motion of Micro Hand Module.", IEEE, January 1, 1993, pp. 1660-1665.	
	B256	ARAI et al., "Development of a New Parallel Manipulator with Fixed Linear Actuator.", In Proceedings of Japan/USA Symposium on Flexible Automation, January 1, 1996, Vol. 1, ASME, New York, pp. 145-149.	
	B257	BAILEY et al., "Imprint Lithography Templates having Alignment Marks," U.S. Patent Application 10/666,527, Filed with USPTO Sept. 18, 2003	
	B258	BENDER et al., "Fabrication of Nanostructures using a UV-based Imprint Technique.", Microelectronic Engineering 53, January 1, 2000, pp. 233-236.	
ACW	B259	CHERALA et al., "Applying Imprinting Material to Substrates Employing Electromagnetic Fields," U.S. Patent Application 10/687,562, Filed with USPTO Oct. 16, 2003	

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Amanda C. Walke

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First Named Inventor	Xu et al.
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Examiner Name	Amanda C. Walke
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ACW	B260	CHOU et al., "Nanoimprint Lithography and Lithographically Induced Self-Assembly.", MRS Bulletin, July 1, 2001, pp. 512-517.	
	B261	Chou, Ultrafast and Direct Imprint of Nanostructures in Silicon, Nature, Col. 417, (June 2002), pp. 835-837.	
	B262	CIBA SPECIALTY CHEMICALS, "What is UV Curing?" www.cibasc.com/image.asp?id=4040	
	B263	COWIE, "Polymers: Chemistry and Physics of Modern Materials.", 2 nd Ed., January 1, 1991, pp. 408-409	
	B264	FEYNMAN, "There's Plenty of Room at the Bottom.", International Appl. No. PCT/US2002/015551	
	B265	GOKAN et al., "Dry Etch Resistance of Organic Materials.", J. Electrochem. Soc.: SOLID-STATE SCIENCE AND TECHNOLOGY, January 1, 1983, pp. 143-146.	
	B266	GOLDFARB et al., "A Well-Behaved Revolute Flexure Joint for Compliant Mechanism Design.",	
	B267	GOLDFARB et al., "Compliant Micromanipulator Design for Scaled Bilateral Telemanipulation of Small-Scale Environments.", ASME International Mechanical Engineering Conference and Exposition, November 1, 1998, DSC-Vol. 64, pp. 213-218.	
	B268	HASHIMOTO et al., "Design and Characteristics of a Parallel Link Compliant Wrist." IEEE, May 1, 1994, Department of Mechanical Engineering, Kagoshima University, pp. 2457-2462.	
	B269	HEIDARI, "Nanoimprint Lithography at the 6 in. Wafer Scale.", J. Vac. Sci. Technol. B 18 (6), November 1, 2000, pp. 3557 - 3560.	
ACW	B270	HEXAPODS, "G1000-PS Power Series", www.hexapods.com .	

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Date Considered

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Application Number	10/763,885
Filing Date	01/23/2004
First Named Inventor	Xu et al.
Group Art Unit	1752
Examiner Name	Amanda C. Walke

Attorney Docket Number P113-55-03

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<i>AM</i>	B271	HEXEL COPORATION, "Tornado 2000 System Specifications.", www.hexel.com , November 12, 1999.	
	B272	HIRAI et al., "Mold Surface Treatment for Imprint Lithography.", Journal of Photopolymer Science and Technology, August 1, 2001, Vol. 14, No. 3, pp. 457-462.	
	B273	HOGAN et al., "Impedance Control: An Approach to Manipulation: Part 1- Theory.", Journal of Dynamic Systems, Measurement, and Control, March 1, 1985, Vol. 107, pp. 1-7.	
	B274	HOLLIS et al., "A Six-Degree-of-Freedom Magnetically Levitated Variable Compliance Fine-Motion Wrist: Design, Modeling, and Control.", IEEE Transactions on Robotics and Automation, June 1, 1991, Vol 7., No. 3, pp. 320 – 332.	
	B275	HOWELL et al., "A Loop-Closure Theory for the Analysis and Synthesis of Compliant Mechanisms.", Journal of Mechanical Design, March 1, 1996, Vol. 118, pp. 121-125.	
	B276	HU et al., "Fluorescence Probe Techniques (FPT) for Measuring the Relative Efficiencies of Free-Radical Photoinitiators.", Macromolecules, May 29, 1998, 31, pp. 4107-4113.	
	B277	International Application No. PCT/US2002/015551, "Communication Relating to the Results of the Partial International Search."	
	B278	International Search Report for PCT/US 00/30041, October 18, 2001.	
	B279	International Search Report for PCT/US 01/26049, February 19, 2002	
	B280	KANETOMO et al., "Robot for Use in Ultrahigh Vacuum.", Solid State Technology, August 1, 1997, pp. 63-72.	
<i>AM</i>	B281	KIM et al., "Surface Energy and Polarity of Treated Indium-Tin-Oxide Anodes for Polymer Light-Emitting Diodes Studied by Contact Angle Measurements." Journal of Applied Physics 1999, pp. 2774-2778, Vol. 86, No. 5.	

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Group Art Unit	1752
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<i>AM</i>	B282	KIM et al., "High-precision Magnetic Levitation Stage for Photolithography.", Precision Engineering, April 1, 1998, Vol 22, No. 2, pp. 66 – 77.	
	B283	KOSEKI, "Design and Accuracy Evaluation of High-Speed and High Precision Parallel Mechanism.", Proc. Of IEEE, January 1, 1998, Intl. Conf. on Robotics & Automation, pp. 1340-1345.	
	B284	KOTACHI et al., "Si-Containing Positive Resist for ArF Excimer Laser Lithography.", Photopolymer Science and Technology, November 4, 1995, pp. 615 – 622.	
	B285	LEE et al., "An Ultraprecision Stage for Alignment of Wafers in Advanced Microlithography.", Precision Engineering, September 1, 1997, pp. 113-122.	
	B286	LEE et al., "Ultra Precision Positioning System for Servo Motor-piezo Actuator Using the Dual Servo Loop and Digital filter Implementation.", American Society for Precision Engineering, January 1, 1998, pp. 287-290.	
	B287	LIN, "Multi-Layer Resist Systems.", Introduction to Microlithography, February 14, 1983, pp. 287-349.	
	B288	LUCAS AEROSPACE, Free-Flex ® Pivot Catalog, January 1, 1999	
	B289	MANSKY et al., "Large-Area Domain Alignment in Block Copolymer Thin Films Using Electric Fields.", Macromolecules, June 9, 1998, Vol. 31, No. 13, pp. 4399-4401.	
	B290	MCMACKIN et al., "A Method of Creating a Turbulent Flow of Fluid between a Mold and a Substrate," U.S. Patent Application 10/898,034, Filed with USPTO July 23, 2004.	
<i>AM</i>	B291	MCMACKIN et al., "A System of Creating a Turbulent Flow of Fluid between a Mold and a Substrate," U.S. Patent Application 10/898,037, Filed with USPTO July 23, 2004.	
<i>AM</i>	B292	MCMACKIN et al., Single Phase Fluid Imprint Lithography Method," U.S. Patent Application 10/677,639, Filed with USPTO Oct. 16, 2003.	

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<i>Am</i>	B293	MERLET, "Parallel Manipulators: State of the Art and Perspectives.", Advanced Robotics, January 1, 1994, Vol. 8, pp. 589-596.	
	B294	MIRKIN et al., "Emerging Methods for Micro-and-Nanofabrication.", MRS Bulletin, July 1, 2001, pp. 506-509.	
	B295	MITTAL, "Precision Motion Control of a Magnetic Suspension Actuator Using a Robust Nonlinear Compensation Scheme.", IEE/ASME Transactions on Mechatronics., December 1, 1997, Vol. 2., No. 4, pp. 268-280.	
	B296	NERAC.COM Retro Search, "Multi-Layer Resists.", September 2, 2004.	
	B297	NERAC.COM Retro Search, "Reduction of Dimension of Contact Holes.", August 31, 2004.	
	B298	NERAC.COM Retro Search, "Trim Etching of Features Formed on an Organic Layer.", September 2, 2004.	
	B299	NGUYEN, "Asymmetric Fluid-Structure Dynamics in Nanoscale Imprint Lithography." The University of Texas at Austin, August 1, 2001, pp. 1-111.	
	B300	OHYA et al., "Development of 3-DOF Finger Module for Micro Manipulation.", Proc. of IEEE, March 1, 1999, Int'l. Conf. on Intelligent Robots and Systems, pp. 894-899.	
	B301	PAPIRER et al., "Abstract of The Grafting of Perfluorinated Silanes onto the Surface of Silica: Characterization by Inverse Gas Chromatography.", Journal of Colloid and Interface Science 159, August 1, 1993, pp. 238-242.	
<i>Am</i>	B302	PARIKH et al., "An Intrinsic Relationship between Molecular Structure in Self-Assembled n-Alkylsiloxane Monolayers and Deposition Temperature.", Journal of Phys. Chem., July 1, 1994, pp. 7577-7590.	
<i>Am</i>	B303	PAROS et al., "How to design Flexure Hinges.", Machine Design, November 25, 1965, pp 151-156.	

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<i>ACW</i>	B304	PENG et al., "Compliant Motion Control of Kinematically Redundant Manipulators.", IEEE Transactions on Robotics and Automation, December 1, 1993, Vol. 9, No. 6, pp.831-837.	
	B305	PERNETTE et al., "Design of Parallel Robots in Microbotics.", Robotica, January 1, 1997, Vol. 15, pp 417-420.	
	B306	PHYSIK INSTRUMENTS, PI Online-Catalog, 1999, from www.physikinstruments.com	
	B307	PHYSIK INSTRUMENTS, Product Catalog for Micropositioning, 1997	
	B308	RAIBERT et al., "Hybrid Position/Force Control of Manipulators.", Journal of Dynamic Systems, Measurement, and Control, June 1, 1981, Vol. 102, pp. 126 – 133.	
	B309	RONG et al., "Design and Analysis of Flexure-Hinge Mechanism Used in Micro-Positioning Stages.", ASME, January 1, 1994, Vol. 2, pp. 979-985.	
	B310	RONG et al., "Dynamics of Parallel Mechanism with Direct Compliance Control.", IEEE, January 1, 1997, pp. 1753-1758.	
	B311	ROOS et al., "Nanoimprint Lithography with a Commercial 4 Inch Bond System for Hot Embossing.", Proceedings of SPIE, October 1, 2001, Vol. 4343, pp. 427-435.	
	B312	SAGIV, "Organized Monolayers by Absorption. 1. Formation and Structure of Oleophobic Mixed Monolayers on Solid Surfaces.", Journal of American Chemical Society/102:1, January 2, 1980.	
	B313	SLOCUM, "Precision Machine Design: Macromachine Design Philosophy and Its Applicability to the Design of Micromachines.", Micro Electro Mechanical Systems, February 4, 1992.	
<i>ACW</i>	B314	SOWAH, Diamond Used to Break the Mould [online], Sept, 18, 2002, [Retrieved on Sept. 2, 2003.] Retrieved from the Internet: <URL: http://eetuk.com/showArticleJhtml?articleID=19203691 >.	

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ACW	B315	SREENIVASAN et al., "An Imprint Lithography System to Produce a Light to Impinge upon and Polymerize a Liquid in Superimposition with Template Overlay Marks," U.S. Patent Application 10/864,214 Filed with USPTO June 9, 2004.	
	B316	SRINIVASAN et al., "Alkytrichlorosilane-Based Self-Assembled Monolayer Films for Stiction Reduction in Silicon Micromachines.", Journal of Microelectromechanical Systems, June 1, 1998, Vol. 7, No. 2, p. 252-260.	
	B317	STEWART, "A Platform With Six Degrees of Freedom.", Proc Instn Mech Engrs, May 28, 1965, Vol 180, Pt1, No. 15, pp. 371-378.	
	B318	STIX, "Getting More from Moores", Scientific American	
	B319	SUNG et al., "Abstract of Micro/nano-tribological Characteristics of Self-Assembled Monolayer and its Application in Nano-Structure Fabrication", Elsevier Science B.V., July 1, 2003, Vol. 255, no. 7	
	B320	SUNG et al., "Micro/nano-tribological Characteristics of Self-Assembled Monolayer and its Application in Nano-Structure Fabrication.", Elsevier Science B.V., July 1, 2003, Vol. 255, No. 7, pp. 808-818.	
	B321	TAJBAKHSH et al., "Three-Degree-of-Freedom Optic Mount for Extreme Ultraviolet.", American Society for Precision Engineering, January 1, 1998, pp. 359-362.	
	B322	TANIKAWA et al., "Development of Small-sized 3 DOF Finger Module in Micro Hand for Micro Manipulation.", Proc. of IEEE, March 1, 1999, Int'l. conf. on Intelligent Robots and Systems, pp. 876-881.	
	B323	TOMITA et al., "A 6-axes Motion Control Method for Parallel-Linkage-Type Fine Motion Stage.", JSPE-58-04, pp. 118-124.	
	B324	Translation of Japanese Patent 02-24848, January 26, 1990.	
ACW	B325	Translation of Japanese Patent 02-92603, April 3, 1990.	

Examiner Signature

Date Considered

6/18/05

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 16 of 17

Complete if Known

Application Number	10/763,885
Filing Date	01/23/2004
First Named Inventor	Xu et al.
Group Art Unit	1752
Examiner Name	Amanda C. Walke
Attorney Docket Number	P113-55-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
ACW	B326	TRILOGY SYSTEMS, "Linear Motors 310.", www.trilogysystems.com, January 1, 2001.	
	B327	US Application No. 10/375,817, Filed 02-27-2003, NGUYEN et al., "Method to Reduce Adhesion between a Polymerizable Layer and a Substrate Employing a Flourine-Containing Layer."	
	B328	US Application No. 10/463,396, Filed 06-17-2003, CHOI et al., "Method to Reduce Adhesion Between a Conformable Region and a Pattern of a Mold."	
	B329	US Application No. 10/735,110, Filed 12-12-2003, NIMMAKAYALA et al., "Magnification Correction Employing Out-of-Plane Distortion of a Substrate."	
	B330	US Application No. 10/785,248, Filed 02-24-2004, CHOI et al., "A Method to Control the Relative Position Between a Body and a Surface."	
	B331	US Application No. 10/788,700, Filed 02-27-2004, SREENIVASAN et al., "Full-Wafer or Large Area Imprinting with Multiple Separated Sub-Fields for High Throughput Lithography."	
	B332	US Application No. 10/806,956, Filed 03-23-2003, CHOI et al., "An Apparatus to Control Displacement of a Body Spaced-Apart from a Surface."	
	B333	US Applications No. 10/194,991, Filed 07-11-2002, SREENIVASAN et al., "Step and Repeat Lithography Processes."	
	B334	US Applications No. 10/687,519, Filed 10-16-2003, NGUYEN et al., "Low Surfaced Energy Template."	
	B335	VANDERBILT UNIVERSITY OFFICE OF TRANSFER TECHNOLOGY; VU9730 Specifications for Improved Flexure Device; 2001, 25, 192-199.	
ACW	B336	WANG et al., "Passive Compliance versus Active Compliance in Robot-Based Automated Assembly Systems.", Industrial Robot, January 1, 1998, Vol. 25, No. 1, pp. 48-57.	

Examiner Signature	<i>Amanda C. Walke</i>	Date Considered	June 8, 2005
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Sheet 17 of 17

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Application Number	10/763,885
Filing Date	01/23/2004
First Named Inventor	Xu et al.
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Attorney Docket Number	P113-55-03

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<i>ANW</i>	B337	WILLIAMS et al., "Six Degree of Freedom Mag-Lev Stage Development.", SPIE, January 1, 1997, Vol. 3051, pp. 856-867.	
	B338	WILLSON et al., "Step and Flash Imprint Lithography", U.S. Patent Application 10/806,051, Filed with USPTO March 22, 2004.	
	B339	WU, "Large Area High Density Quantized Magnetic Disks Fabricated Using Nanoimprint Lithography.", J. Vac. Sci. Technol., November 1, 1998, B 16(6), pp. 3825-3829.	
	B340	XIA et al., "Soft Lithography.", Annu Rev. Mater Sci. 1998 28: 153-184	
	B341	XIA et al., "Soft Lithography.", Angew. Chem. Int. Ed., January 1, 1998, pp. 551-575.	
	B342	XU et al., "Materials for Imprint Lithography," U.S. Patent Application 10/784,911, Filed with USPTO Feb. 23, 2004.	
<i>ACW</i>	B343	XU et al., "Methods for Fabricating Patterned Features Utilizing Imprint Lithography,: U.S. Patent Application 10/694,284, Filed with USPTO Oct., 27, 2003.	

Examiner Signature

Amanda C. Walke

Date Considered

June 8, 2005

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STATEMENT BY APPLICANT

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Sheet 1 of 5

APPLICATION NUMBER	10/763,885
FILING DATE	01/23/2004
FIRST NAMED INVENTOR	Xu et al.
Group Art Unit	1752
Examiner Name	Walke, Amanda C.
Attorney Docket Number	P113-55-03

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (If known)			

<i>ACW</i>	C1	6,391,217	B2	Schaffer et al.	5/21/2002	
	C2	2004/0007799	A1	Choi et al.	1/15/2004	
	C3	2004/0021254	A1	Sreenivasan et al.	2/5/2004	
	C4	2004/0021866	A1	Watts et al.	2/5/2004	
	C5	2004/0022888	A1	Sreenivasan et al.	2/5/2004	
	C6	2002/0177319	A1	Chou	11/28/2002	
	C7	6,518,189	B1	Chou	2/11/2003	
	C8	2004/0192041	A1	Jeong et al.	9/30/2004	
	C9	6,828,244	B2	Chou	12/7/2004	
	C10	6,809,356	B2	Chou	10/26/2004	
	C11	2004/0197843	A1	Chou et al.	10/7/2004	
	C12	2004/0156108	A1	Chou et al.	8/12/2004	
	C13	2004/0137734	A1	Chou et al.	7/15/2004	
	C14	2004/0131718	A1	Chou et al.	7/8/2004	
	C15	2004/0116809	A1	Chou et al.	6/24/2004	
	C16	2004/0046288	A1	Chou	3/11/2004	
<i>ACW</i>	C17	2003/0080472	A1	Chou	5/1/2003	
<i>ACW</i>	C18	2003/0034329	A1	Chou	2/20/2003	

Examiner Signature

AMC Walke

Date Considered

June 8, 2005

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Sheet	2	of	5		

U.S. PATENT DOCUMENTS						
Examiner Initials ¹	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
<i>MW</i>	C19	2002/0042027	A1	Chou et al.	4/11/2002	
	C20	5,594,042		Glover et al.	1/14/1997	
	C21	5,629,095		Bujanowski et al.	5/13/1997	
	C22	5,861,467		Bujanowski et al.	1/19/1999	
	C23	5,331,020		Brown et al.	7/19/1994	
	C24	4,617,238		Crivello et al.	10/14/1986	
	C25	6,580,172	B2	Mancini et al.	6/17/2003	
	C26	11/012,374		Xu et al.	12/15/2004	
	C27	4,512,848		Deckman et al.	4/23/1985	
	C28	6,517,995	B1	Jacobenson et al.	2/11/2003	
	C29	2004/0110856	A1	Young et al.	6/10/2004	
	C30	11/068,174		Xu et al.	2/28/2005	
	C31	5,028,366		Harakal et al.	7/2/1991	
	C32	5,601,641		Stephens	2/11/1997	
	C33	5,849,209		Kindt-Larsen et al.	12/15/1998	
	C34	5,849,222		Jen et al.	12/15/1998	
<i>↓</i>						
<i>MW</i>						

Examiner Signature	<i>Amanda C. Walk</i>	Date Considered	<i>June 8, 2005</i>
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Substitute for form 1449A/PTO				<i>Complete if Known</i>	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				APPLICATION NUMBER 10/763,885 FILING DATE 01/23/2004 FIRST NAMED INVENTOR Xu et al. Group Art Unit 1752 Examiner Name Walke, Amanda C.	
Sheet	3	of	5	Attorney Docket Number	P113-55-03

FOREIGN PATENT DOCUMENTS

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		Office ²	Number ⁴	Kind Code ⁵ (if known)			

Examiner Signature		Date Considered	June 8, 2005
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT					
(use as many sheets as necessary)					
Sheet	4	of	5	Examiner Name	Walke, Amanda C.
				Attorney Docket Number	P113-55-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²

<i>AM</i>	C41	Colburn et al., Step and Flash Imprint Lithography for sub-100 nm Patterning, Proceedings of SPIE Vol. 3997, pp. 453 - 457, 1/1/2000	
	C42	Papirer et al., The Grafting of Perfluorinated Silanes onto the Surface of Silica: Characterization by Inverse Gas Chromatography, Journal of Colloid and Interface Science 159, pp.238-242, 8/1/1993	
	C43	Chou et al., Nanoimprint Lithography, Journal of Vacuum Science Technoloy B 14(16), pp. 4129-4133, 11/1/1996	
	C44	Colburn et al., Development and Advantages of Step-and-Flash Lithography, Solid State Technology, 7/1/2001	
	C45	Colburn et al., Characterization and Modeling of Volumetric and Mechanical Properties for Step and Flash Imprint Lithography Photopolymers, Journal of Vacuum Science Technology. Vol b. 19(6), 11/1/2001	
	C46	Yu et al., Properties of Fluorinated Amorphous Diamond Like Carbon Films by PECVD, Applied Surface Science 219 (3-4); pp. 228-237, 12/1/2003	
	C47	Compon et al., Electroanalysis at Diamond-Like and Doped-Diamond Electrodes, Electroanalysis 15(17); pp. 1349-1363, 9/1/2003	
	C48	Mansano et al., Protective Carbon Layer for Chemical Corrosion of Stainless Steel, Diamond and Related Materials 12 (3-7); pp. 749-752, 3/1/2003	
<i>AM</i>	C49	Butter et al., Production and Wetting Properties of Fluorinated Diamond-Like Carbon Coatings, Thin Solid Films, 311(1-2); pp. 107-113, 12/31/1997	

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<i>AM</i>	C50	Hakovirta et al., Heat Resistance of Fluorinated Diamond-Like Carbon Films, Diamond and Related Materials 10(8); pp. 1486-1490, 8/1/2001	
	C51	Zhu et al., The Improvement of the Oxidation Resistance of TiAl Alloys by Fluorine Plasma-Based Ion Implantation, Surface and Coatings Technology 158; pp. 502-507, 9/1/2002	
	C52	Yao et al., Structural, Mechanical and Hydrophobic Properties of Fluorine-Doped Diamond-Like Carbon Films Synthesized by Plasma Immersion Ion Implantation and Deposition (PIII-D), Applied Surface Science 230; pp. 172-178, 4/17/2004	
	C53	Bailey et al., Step and Flash Imprint Lithography: Defect Analysis, Journal of Vacuum Science, B 19(6), pp. 2806-2810, 11/1/2001	
	C54	Bailey et al., Step and Flash Imprint Lithography: Template Surface Treatment and Defect Analysis, Journal of Vacuum Science, B 18(6), pp. 3572-3577, 11/1/2000	
	C55	Schneider et al., Stripes of Partially Fluorinated Alkyl Chains: Dipolar Langmuir Monolayers	
<i>AM</i>	C56	Bender et al., Multiple Imprinting in UV-based Nanoimprint Lithography: Related Material Issues, Microelectronic Engineering 61 - 62, pp. 407 - 413, 1/1/2002	

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